

The Opti™ RF power rack is a modernized solution for 200 mm semiconductor fabs using high-density plasma chemical vapor deposition (HDP/CVD) tools. It utilizes high-performance generators combined with real-time data collection capability, providing the intelligence needed to monitor generator health and optimize processes.

Features

- High-performance AE generators with > 70% efficiency at full power
- Real-time HMI dashboard
- Built-in safety including EMO switch, leak detection, smoke detection, and overcurrent protection
- Optional remote access within secure fab networks

What's Included

- One Paramount generator (13 MHz, 5 kW)
- Two Paramount Plus generators (2 MHz, 5kW)
- HMI dashboard (touch screen)
- Embedded PowerInsight
- Analog adapter cables
- Lift hooks and leveling feet

Benefits

- Higher process stability and efficiency from advanced RF power delivery
- View live system data and historical data (up to one hour), temperature charts, and time-stamped fault and warning history from each generator
- Significant ROI in operating cost and tool downtime
- Versatile design for easy accessibility and serviceability



The PowerInsight HMI gives real time power, frequency, fault, and temperature data.



Paramount® generator



Paramount Plus generator

For Global Services contact information, visit advancedenergy.com

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